Probe Software

Software for MicroAnalysis

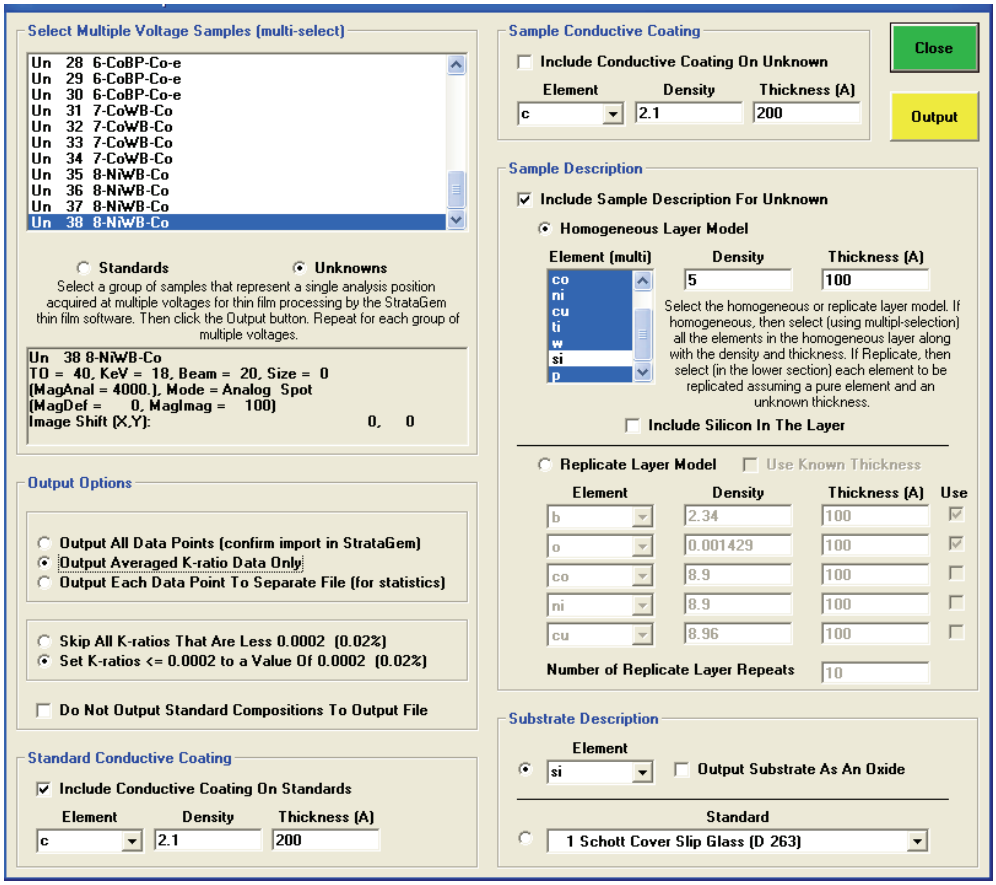
Probe Software, Inc.
885 Crest Dr
Eugene, OR 97405 USA
(541) 343-3400
(541) 485-7901 (FAX)
sales@probesoftware.com
www.probesoftware.com

Thin Film Acquisition/Analysis

Probe for EPMA Thin Film Acquisition and Analysis

Probe for EPMA provides optimized capabilities for rapid and automated acquisition and accurate quantitative analysis of thin film materials on electron opaque substrates (and unsupported films).

By utilizing Multi-Voltage-Analysis (MVA), Probe for EPMA can automatically acquire multiple data sets at optimized electron beam energies to simultaneously determine both thickness and composition in thin film materials of all compositions and thicknesses.



Based on work by Pouchou and Pichior, this robust and flexible MVA method even allows for the accurate determination of multiple layers on substrates with excellent accuracy. Due to the superb sensitivity of EPMA, film thicknesses down to a few nanometers can be also characterized with confidence. In cases where the same element is present in both the film and substrate, e.g., Si/Ge on Si wafers, this method can be combined with x-ray reflectivity (XRR) to robustly determine the unknown composition even on complex and insulating substrates such as Dow 1737 FPD glass.

Contact: John Donovan, donovan@probesoftware.com or call (541) 343-3400 for more information.

03-12-2012